Claims

What is claimed is:

1. A method of fabricating a MEMS device with controllable structural characteristics, comprising:

identifying structural requirements of one or more structures of a MEMS device;

determining a first geometric pattern;

determining a second geometric pattern; and

etching a plurality of holes into the MEMS device, wherein a first subset of the plurality of holes etched into the MEMS device corresponds to the first geometric pattern and a second subset of the plurality of holes etched into the MEMS device corresponds to the second geometric pattern.

2. The method of claim 1, further comprising filling the first subset of the plurality of holes with an absorbent material.

3. The method of claim 1, further comprising filling the second subset of the plurality of holes with an absorbent material.

4. The method of claim 1, wherein the first geometric pattern comprises one or more of: squares; triangles; circles; honeycombs; rectangles; and slots.

5. The method of claim 1, wherein the second geometric pattern comprises one or more of: squares; triangles; circles; honeycombs; rectangles; and slots.

6. The method of claim 1, further comprising:

determining a third geometric pattern; and

wherein a third subset of the plurality of holes corresponds to the third geometric pattern.